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José Sasián
Richard N. Youngworth
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Introduction

The 2010 Optical System Alignment, Tolerancing, and Verification IV conference was again a great success. The optics and photonics community continued to show great support by presenting and submitting excellent talks, posters, and papers. The attendance and enthusiasm displayed at the sessions indicated that the conference topics are current and of value to the optics community.

This year the conference had four strong sessions on optomechanics and tolerancing; the James Webb Space Telescope (JWST); alignment and optical system analysis; and verification, inspection, and metrology. The conference started on a high note with excellent papers on optical system development, lens centering, mirror surface figure tolerance assignment, and general relationships for axial misalignment in optical systems. The JWST session included papers on the telescope integration and alignment as well as papers on specific testing for the instruments and the Integrated Science Instrument Module (ISIM). The afternoon had papers on general alignment procedures in addition to specific cases of building diverse systems for the National Ignition Facility (NIF), the Advanced Technology Solar Telescope (ATST), and a three mirror anastigmat system. The oral sessions concluded with papers on optomechanics, a high-precision system for passive ranging metrology, and wafer inspection. We were also pleased to have posters presented on a variety of subjects including a study of linear mechanical stages, alignment and integration of an adaptive optics system, scattering, and a solar concentration system. It was actually very difficult to find a specific highlight for the conference due to the high quality of the presentations and posters!

We wholeheartedly thank our program committee for the support they have given in promoting the conference. We are also grateful to all of the authors for sharing their work, the audience for participating and interacting with the authors and community, and SPIE for providing us the opportunity to cover the subjects of optical system alignment, tolerancing, and verification in a dedicated conference and proceedings.

We will be running this conference again in 2011. We encourage everyone interested in these subjects to please submit their work and attend the sessions. Also, please feel free to contact us or anyone on our program committee if you have any questions. All the best and see you next year.

José Sasián
Richard N. Youngworth